Docket No. 34261-8500

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

nge Application of:

Howard Ge et al.

MAR 1 4 2005

Serial No.: 10/680,960

Filed: 10/07/2003

For: PHOTORESIST COASTING PROCESS FOR

MICROLITHOGRAPHY

Examiner:

Group Art Unit: 1756

March 10, 2005

Irvine, California 92614

INFORMATION DISCLOSURE STATEMENT

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, Virginia 22313-1450

Dear Sir:

In an attempt to fully comply with the duty of disclosure set forth in 37 C.F.R. § 1.56 and in conformance with 37 C.F.R. §§ 1.97 and 1.98, applicant wishes to bring to the attention of the U.S. Patent Office the following references, which was found during the prosecution of a co-pending PCT International Patent Application:

U.S. Patent No. 5,032,217

U.S. Patent No. 2,046,596

U.S. Patent No. 5,455,062

U.S. Patent No. 5,498,449

U.S. Patent No. 6,403,500

U.S. Patent Application Publication No. 2002/0092917

European Patent Application No. EP 0 654 306

Patent Abstracts of Japan Publication No. 11-010041

KUTCHOUKOV V G ET AL.: "New photoresist coating method for 3-D structured wafers" SENSORS AND ACTUATORS A, ELSEVIER SEQUOIA S.A., LAUSANNE, CHI, vol. 85, no. 1-3, 25 August 2000 pages 377-383.

Copies of the foreign references, Kutchoukov et al. article and form PTO-A820 are attached.

The undersigned attorney hereby certifies that each item contained in the Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart international application not more than three months prior to filing this statement.

If the Examiner believes that a telephone conference would help further the prosecution of this case, he is respectfully requested to contact the undersigned attorney at the listed telephone number.

I hereby certify that this correspondence is being deposited with the U.S. Postal Service as first class mail in an envelope addressed to: Mail Stop, Commissioner for Patent, PO Box 1450, Alexandria, VA 22313-1450 on March 10, 2005

by: Melissa Gamarra

Signature

Date of Signature: March 10, 2005

Very truly yours,

SNELL & WILMER LLP

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	INFO	RMATION DISCLOSUR	E CITATION	~ (CO)	Applicant(s) Howard Ge et al.					
	INFORMATION DISCLOSURE CITATION (Use several sheets if necessary) MAR 1			905 y	Filing Date		Group Art Unit			
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•			A Banalis	SEATENT	DOCUMENTS					
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME		CLASS	SUBCLASS		DATE OPRIATE	
		5,032,217	7/16/1991	Tanaka						
		2,046,596	7/7/1936	Zwiebel						
	_	5,455,062	10/3/1995	Muhlfriedal et al.						
		5,498,449	3/12/1996	Bae	-					
		6,403,500	6/11/2002	Yu et al	l.					
U.S. PATENT APPLICATION PUBLICATIONS										
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	,	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE		
		2002/0092917	7/18/2002	Ko et al.						
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			FORE	IGN PATE	NT DOCUMENTS					
	REF	DOCUMENT NUMBER	DATE	Patent Abstracts of Japan Europe		CLASS	SUBCLASS	Translation YES NO		
		11-010041	19-01-1999					1		
		0 654 306	27-05-1994					1		
			OTHER D	OCUMEN	TS (Including Author,	Title, Date, F	Pertinent Pages, E	tc.)		
		KUTCHOUKOV V G	ET AL.: "New ph	otoresist c	oating method for 3-D stru I, vol. 85, no. 1-3, 25 Augus	ctured wafe	rs" SENSORS	ANDACT	UATORS	
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not conside	reu. IN	clude copy of this form with next	communication to	applicant.						

Form PTO-A820 (also form PTO-1449)